WHAT IS CLAIMED IS:

15

25

- 1-17 (Canceled)
- 18. (New) A process for forming nanostructures comprising the step of applying on localised regions of a smooth thin film of bistable or multistable molecules an external perturbation with preset magnitude thereby said film undergoes a collective morphological transformation and nanostructures are formed by selforganisation of said molecules, said nanostructures having preset number, size, interspacing and shape.
- 19. (New) A process according to claim 18, wherein said nanostructures are in the form of dots when said regions are one-dimensional and said nanostructures are in the form of strips when said regions are two-dimensional.
 - 20. (New) A process according to claim 19, wherein said dots are formed with a density, inter-dot distance or pitch and size controlled by presetting a thickness of said thin film.
 - 21. (New) A process according to claim 19, wherein said dots are formed in a number controlled by presetting a length of said regions.
 - 22. (New) A process according to claim 18, wherein the nanostructures are organised in the form of arrays of nanostructures.
- 23. (New) A process according to claim 19, wherein said dots are formed and used to code and store information with areal densities of 1-1000 Gbpsi.
 - 24. (New) A process according to claim 18, wherein said perturbation is selected from a mechanical perturbation, a thermal perturbation, a thermomechanical perturbation, an electrical perturbation, a magnetic perturbation, a perturbation made with light or combinations thereof.
 - 25. (New) A process according to claim 18, wherein said perturbation is applied with a scanning probe microscope (SPM).
- 26. (New) A process according to claim 18, wherein the perturbation is applied with mechanical devices, millipedes or actuators able to produce

multiple local perturbations.

5

15

25

- 27. (New) A process according to claim 18, where in said perturbation is applied with an optical microscope, or related system, a scanning confocal microscope, or photolithography setups.
- 28. (New) A process according to claim 18, wherein said perturbation is applied with a rigid stamp or with a flexible stamp with which a load force is applied on said film regions, said load force being in the range of 0.1 to 100 kg/cm².
- 29. (New) A process according to claim 18, wherein said 10 morphological transformation of said thin film is obtained by wetting/dewetting transition, dewetting introducing spatial correlation, particularly spinodal dewetting, crystallisation or formation of intermediate metastable structures.
 - 30. (New) A process according to claim 18, wherein said molecules are selected from the group consisting of rotaxanes, partcularly rotaxane 3, and rotaxanes terminated with optically /electrically active groups and conjugated stoppers.
 - 31. (New) A process according to claim 18, wherein said molecules are selected from the class of catenanes.
- 32. (New) A process according to claim 18, wherein said molecules are selected from molecules having an isomerizable double bond, particularly molecules containing a linear C=C bond with cis-trans isomerisation, azo e diazo groups.
 - 33. (New) A process according to claim 18, wherein said molecules are selected from molecular motors and actuators and biological motors, particularly actine, miosine, oligopeptides, DNA, RNA and oligonucleotides.
 - 34. (New) A process according to claim 18, wherein said thin film is deposited on a substrate or is grown on a substrate form solution, or from vapour phase, or from reactive precursors, or by sublimation.